

Serial No.: 10/501,911  
Atty. Docket No.: P69949US0

**IN THE SPECIFICATION:**

On page 29, please amend the last paragraph beginning on line 28, through the first paragraph on page 31 which ends on line 13, as follows:

--Figures 2a-2d show cross-sectional views of three different cantilever sensors according to the invention. The cantilever sensors comprise a primary substrate 21a, 21b, 21c, 21d and a cantilever 24a, 24b, 24c, 24d respectively. The respective cantilevers are connected to the respective pillars in a stem line 29a, 29b, 29c, 29d. In the cantilever sensor shown in Figure 2a, a surface stress sensing element 23a, e.g. a piezoresistor such as a horseshoe-shaped piezoresistor, is incorporated into the cantilever unit 24a, and a pair of parallel wires 22a is integrated into the primary substrate as vertical wires, i.e. the wires 22a have an angle to the uppermost surface 28a of the primary pillar shaped substrate ~~28a~~ 21a which is about 90° and they pass through the primary substrate and exit at its lowermost surface 27a. The uppermost surface 28a of the primary substrate ~~28a~~ 21a and the upper surface 25a of the cantilever unit ~~25a~~ 24a are parallel and in direct prolongation of each other.

In the cantilever sensor shown in Figure 2b, a ~~not shown~~ surface stress sensing element 23b, e.g. a piezoresistor such as a

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horseshoe-shaped piezoresistor, is incorporated into cantilever unit 24b as in Figure 2a, and a pair of ~~not shown~~ parallel wires 22b is integrated into the primary substrate 21b as in Figure 2a. The uppermost surface 28a of the primary substrate ~~28b~~ 21b has an angle  $x^\circ$  to the upper surface 25b of the cantilever ~~25b~~ 24b which angle is less than 180, namely between 180 and 135°.

The cantilever sensor shown in Figure 2c is identical to the cantilever sensor shown in Figure 2b except that the uppermost surface 28c of the primary substrate ~~28c~~ 21c has an angle  $x^\circ$  to the upper surface 25c of the cantilever ~~25c~~ 24c, which angle is higher than 180, namely between 180 and 225°.

In the cantilever sensor shown in Figure 2d, a surface stress sensing element 23d, e.g. a piezoresistor such as a horseshoe-shaped piezoresistor, is incorporated into the cantilever unit 24d, and a pair of parallel wires 22d is integrated into the primary substrate 21d at a small angle, e.g. 10° to the vertical direction, i.e. the wires ~~22a~~ 22d have an angle to the uppermost surface 28d of the primary pillar shaped substrate ~~28d~~ 21d which is about 80° and they pass through the primary substrate and exit at its lowermost surface 27d. The uppermost surface 28d of the primary substrate ~~28d~~ 21d and the upper surface 25d of the cantilever unit ~~25d~~ 24d are parallel and in direct prolongation of each other.--

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On page 34, after the last line, please insert the following new paragraph:

--The invention being thus described, it will be apparent that the same may be varied in many ways. Such variations are not to be regarded as a departure from the spirit and scope of the invention, and all such modifications as would be recognized by one skilled in the art are intended to be included within the scope of the following claims.--.